



MEMS and Piezoelectric Sensors for Biomedical Applications

Guest Editors:

Dr. Tung-Li Hsieh

Department of Electronics
Engineering, National Kaohsiung
University of Science and
Technology, Kaohsiung 80778,
Taiwan

Prof. Dr. Jau-Woei Perng

Department of Mechanical and
Electro-Mechanical Engineering,
National Sun Yat-sen University,
Kaohsiung 804, Taiwan

Dr. Cheng-Yan Guo

Accurate Meditech Inc., New
Taipei 241406, Taiwan, China

Deadline for manuscript
submissions:

closed (31 December 2023)

Message from the Guest Editors

Dear Colleagues,

This Special Issue focuses on advanced MEMS and piezoelectric sensors research for the vital sign monitoring of wearable devices, emphasizing their advantages for wearable device design. Furthermore, the issue analyzes the contribution of continuous vital sign monitoring to the research in biomedicine and the advantages of compact wearable device design for health technology. Our primary goal is to collect research and review articles that include novel wearable device designs, scientific method-based analyses, and contributions to the biomedical field and medical technology.

We look forward to receiving your submissions!

Dr. Tung-Li Hsieh
Prof. Dr. Jau-Woei Perng
Guest Editors

Dr. Cheng-Yan Guo
Guest Editor Assistant





an Open Access Journal by MDPI

Editor-in-Chief

Prof. Dr. Ai-Qun Liu

1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Author Benefits

Open Access: free for readers, with article processing charges (APC) paid by authors or their institutions.

High Visibility: indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

Journal Rank: JCR - Q2 (*Physics, Applied*) / CiteScore - Q2 (*Mechanical Engineering*)

Contact Us

Micromachines Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland

Tel: +41 61 683 77 34
www.mdpi.com

mdpi.com/journal/micromachines
micromachines@mdpi.com
[X@micromach_mdpi](https://twitter.com/micromach_mdpi)